

FORM 1449 INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)	Atty. Docket No. P29771	Application No. 10/576,023
	Applicant Kimiaki TOSHIKIYO	
	I.A. Filing Date December 15, 2004	Group 2622

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	A	5561558	10/01/1996	Shiono et al.			
	B	5742433	04/21/1998	Shiono et al.			
	C	2003/0179457	09/25/2003	Dobashi et al.			
	D	7250973	07/31/2007	Dobashi et al.			
	E						
	F						
	G						
	H						
	I						
	J						
	K						
	L						
	M						

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES	ENGLISH ABSTRACT YES
	N	2003-243638	08/29/2003	JAPAN				X
	O	2004-096358	03/25/2004	JAPAN				X
	P	7-113907	05/02/1995	JAPAN				X
	Q	7-113906	05/02/1995	JAPAN				X
	R							
	S							
	T							
	U							

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	1	Donald C. O'Shea et al., "Diffraction Optics Design, Fabrication, and Test", SPIE PRESS, pp.54-56, 12/29/2003.
	2	Toshikiyo et al., "A MOS Image Sensor with Microlenses Built by Sub-Wavelength Patterning", 2007 IEEE ISSCC session 28.8 K, 02/14/2007.
	3	JAPAN Office action, mail date is 03/22/2011.
	4	Response to an Office Action to the corresponding Chinese patent application No. 200480042730.2 (with a partial English translation of relevant portion).
	5	

EXAMINER	DATE CONSIDERED
*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609: draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	